

Notice of References Cited	Application/Control No. 10/623,052		Applicant(s)/Patent Under Reexamination FUJII ET AL.	
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X	C	US-6,728,091	04-2004	Tsuruta et al.	361/234
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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